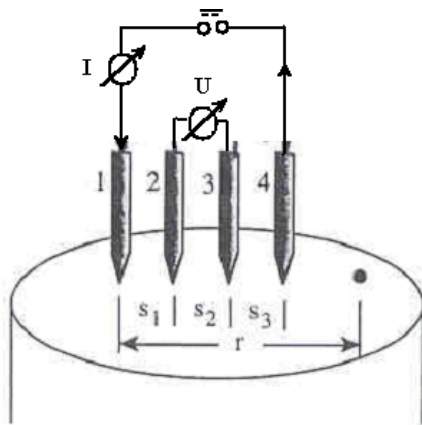


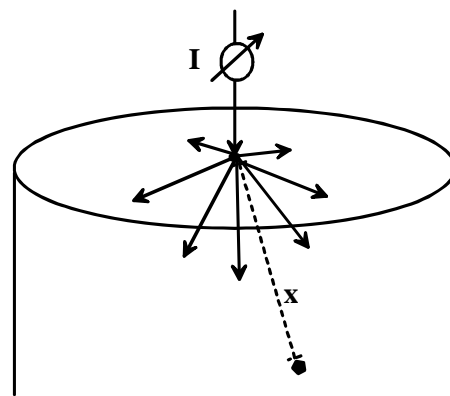
## Exercises "Electronic Materials"

#2

### Exercise 2: The four-point probe



(left): Collinear four point probe.



(right): Current  $I$  enters a semi-infinite sample through one probe.

To measure the resistivity  $\rho$  of wafers, thin films etc., the four-point-probe method is mostly used. The left part of the figure shows a collinear four-point probe arrangement. A current is flowing from probe 1 to probe 4. Between probe 2 and 3 the voltage drop is measured. The current and voltage are measured with different probe pairs, because if one would measure the voltage between probe 1 and 4 as well, one would measure a lot higher resistance than the simple material resistance.

- a) Write down qualitatively the resistance chain between probe 1 and 4.

We first calculate the current and electrical field distribution for one probe (probe 1), from which the current  $I$  is flowing into an idealized *semi-infinite* sample (cf. right part of the figure) of constant resistivity  $\rho$ :

- b) Show that the current density at a distance  $x_1$  from probe 1 is given by  $j(x_1) = \frac{I}{2\pi x_1^2}$ .

- c) Calculate the electrical field strength distribution  $E(x_1)$  by using Ohm's law

(Solution:  $E(x_1) = \frac{\rho I}{2\pi x_1^2}$ ).

- d) The reference potential at infinite distance from the probe is  $U_\infty := 0$  V. Derive that

the potential at distance  $x_1$  from the probe is  $U(x_1) = -\frac{\rho I}{2\pi x_1}$ .

Probe 4 can be treated similar to probe 1, the only difference is that  $I$  is negative because the current is leaving the sample there.

- e) Explain shortly why you are allowed to sum up the potentials “originating” from probe 1 and 4!
- f) Determine the potential at a distance  $x_4$  from probe 4 where the current  $I$  leaves the sample!
- g) Show that the potential difference between probe 2 and 3 is  $\Delta U = -\frac{\rho I}{2\pi s}$ , if they are equally spaced (spacing  $s$ ).
- h) What is the resistivity  $\rho$  of the sample?

This example can be generalized to account for arbitrarily shaped samples: The resistivity can then be formulated as  $\rho = F \frac{V}{I}$ , where  $F$  is a geometrical correction factor (in the case of a semi-infinite sample:  $F = 2\pi s$ ). For a thin sample, a thickness  $t \leq \frac{s}{2}$ , a measurement in the middle of the sample, and a sample's lateral extension of at least  $4s$ ,  $F = \frac{t\pi}{\ln 2}$  results, i.e. the measurement is independent of the probe spacing  $s$ !

- i) For a commercially available semiconductor wafer with  $t = 525 \text{ } \mu\text{m}$ , a voltage  $U = 12 \text{ mV}$  is measured for a current  $I = 10 \text{ mA}$ . Calculate the resistivity  $\rho$  of the wafer!